Sealed Bid|Major Solar Sealed Bid Sale

Starting: January 11, 2011
Ending: February 28, 2011
On Behalf Of: Hewlett-Packard
Location: 1000 NE Circle Blvd. Corvallis, OR 97330

Accepting all bids now!

Key Assets:

Credence ASL3000 System power supply module. Test head with 30 instrument card slots and support for the RF option with MVNA; ASL series Clock support; Test head interface card with multi-site handler interface; Full Feature Manipulator; Test Head Slots include: 1 ASL3RFE 4P/ 6 GHz, 4-port RF Subsystem; 1 ASL3RF SMC/GA AUX SMG OAATE RF Source, Auxiliary 3; 1 ASL3RF PBCAL Gigatronics RF Probe; 1 ASL3 MDI Modular Digital Instrument, 16 channels, 50 MHz, 2nd MDI available;; 1 ASL3 DVI-300 Dual Voltage/Current Resource, 300mA; 1 ASL3 CAL DUT System Calibration Board 7; 1 ASL3RF VCAL Vector Calibration Kit 8; Controller and software, (software relicenses and OEM may be required); Microsoft Windows NT PC with Intel Pentium III processor; 20 GB hard disk drive; 1.44 MB floppy disk drive; CD ROM drive; 512 MB memory; 15-inch LCD flat panel monitor; 101-key keyboard; keyboard; RS232 interface port, parallel printer port; Visual ATE System; Software with Credence test program development environment; Microsoft Visual C++; Integrated calibration and diagnostic software; Graphical debug package with Auto code; there is an DVI-300 board in the configuration; Test Head Slots include: 1 ASL3RFE 4P/ 6 GHz, 4-port RF Subsystem; 1 ASL3RF SMC/GA AUX SMG OAATE RF Source, Auxiliary 3; 1 ASL3RF PBCAL Gigatronics RF Probe; 1 ASL3 MDI Modular Digital Instrument, 16 channels, 50 MHz, 2nd MDI available;; 1 ASL3 DVI-300 Dual Voltage/Current Resource, 300mA; 1 ASL3 CAL DUT System Calibration Board 7; 1 ASL3RF VCAL Vector Calibration Kit 8 . Vintage: Late 2003/ Early 2004. SN# B00136. Equipment Located in Taiwan.

Nikon NSR-2005 i10C Litho-i-line Stepper, Wafer size 200mm. Vintage: Nov. 1994. SN# 1004106. Inventory ID# AA10333. Tool ID# Stepnik-31-IBM. Equipment Located in Nijmegen, The Netherlands.

KLA-Tencor AIT Metrology-Particle: 200mm wafer. Vintage: 11/1998. SN# 1697-8141. Tool ID# D214419. Equipment is Located in Nijmegen, The Netherlands.

Hitachi S-8820 CD measuring size: 200-250nm, consistently; Electron Gun = Schottky emission source; Accelerating voltage = 700V to 1300V, 10V steps; Probe current: 1-15pA with automated setting and measurement by Faraday cup, 1.8pA at 800V or 1-16pA with optional retarding voltage), 1-10pA at 1000V, 1-15pA at 1300V; 3 Stage Electromagnetic Lens System; Objective Lens: 4 opening click stop, heated aperture that is selectable and adjustable outside the vacuum system; 2-Stage Deflection Scan Coil: Astigmatism correction via an 8-pole electromagnetic coil;Cassette Flipper Option (2 flippers - one per load port). Vintage: 1/1/1996. Tool ID# CD.007. Equipment is Located in Nijmegen, The Netherlands.

TEL Alpha-8S-Z LP-CVD TEOS Furnace, 200mm. Vintage: 11/1/2000. SN# A0000000XD282. Equipment is Located in Shiga, Japan.

Nikon NSR-2005 i9A Litho-i-line Stepper. Wafer size 150mm. Vintage: Aug. 1991. SN# 900001. Inventory ID# AA10229. Tool ID# Stepnik-14. Equipment Located in Nijmegen, The Netherlands.

DNS SD-80BW Litho-Developer; 200mm wafer. Vintage: 1/1/1996. SN# 56700-3393. Tool ID# D214063. Equipment is Located in Nijmegen, The Netherlands

Teradyne Catalyst Base (Sea); IEEE BUS+EXP., RS232; Isolation Transformer; 384/20 TEST HEAD (Total 320 digital pins installed); Advanced Time Measurement System (MF & TH); Manual Pendant Start Switch; Image Tester Initial Annual Update License; Solaris 2.5 Compiler for Image; Solaris Operating System; Digital Signal IO (DSIO) License; Catalyst Tester Software; Selected Base Options; 415V AC, 50 HZ, 180 W/256 MB RAM/TERA/BUS Control Interfaces, Ultra Integration Kit w/Public Ethernet Interface, I/F Prod Comp w/256 MB RAM, 20 GB Disk,CD-ROM Drive; Digital; 384-Channel Digital Subsystem(MF & TH), 8 Channel Digital TH Control Card, 16 Channel Catalyst DIG Mainframe (416M PAT Depth; 16 MEG Pattern Depth License (100, 200, 400), Scan License(System Enabler), DC Instrumentation and Support- High Current Unit #1 (30V/2A), High Current Unit #2 (30V/2A), High Current Unit #3 (30V/2A), Expansion Cabinet and UBS Kit (System), 4-Pin Advanced Analog Pin Unit (AAPU), Programmable UBVI (60V/200MA).

Applied Materials: Model: 5000 CVD; Process-CVD-TEOS. Wafer size 200mm. Vintage: 1995 SN# 8832. Tool ID # D214362 Configuration: 1x NPECVD Chamber, 1 x CVD TEOS BPSG Chamber Equipment located in Nijmegen, The Netherlands

KLA Tencor: Model: Koethley Quantox; Process-Metrology-Films. Wafer size 200mm Vintage: 1997 SN# Q7038 Tool ID# KTH-QTX-1 Equipment Located in Nijmegen, The Netherlands

Lam Research; Model: Rainbow 4425 process- Etch-Poly Wafer size 150mm SN# 2717; Tool ID # Lam-44C-ATA2 Equipment located in Nijmegen, The Netherlands

Hitachi; Model S-7800 Process-Metrology- CD Wafer size 200mm Vintage; 1996 SN# 5005-03. Tool ID# D214513 Equipment located in Nijmegen, The Netherlands

Lam Research; Model; Rainbow 4500 Process-Etch-Oxide, Wafer size 150mm SN# 2172; Tool ID# LAM-45A-ATA2 Equipment located in Nijmegen, The Netherlands

Lam Research; Model; Rainbow 4500 Process-Etch-Oxide, Wafer size 150mm SN# 2223; Tool ID# LAM-45B-ATA2 Equipment located in Nijmegen, The Netherlands

Lam Research; Model; Rainbow 4500 Process-Etch-Oxide, Wafer size 150mm SN# 2212 Tool ID# LAM-45C-ATA2 Equipment located in Nijmegen, The Netherlands

Lam Research; Model; Rainbow 4500 Process-Etch-Oxide, Wafer size 150mm SN# 2213 Tool ID# LAM-45D-ATA2 Equipment located in Nijmegen, The Netherlands

KLA Tencor; Model: Thermawave OP-2600 Process-Metrology-Films. Wafer size 150mm Vintage: 1993 SN# 6062 Tool ID# T-Wave-1 Equipment located in Nijmegen, The Netherlands

KLA-Tencor: Model: Thermawave OP-2600 Process-Metrology-Films,. Wafer size 200mm Vintage: 1996 SN# 6343 Tool ID# D207649 Equipment located in Nijmegen, The Netherlands

DNS MP-2000 Wet-Sign Processor; Vintage: Sept. 2000, 200mm wafer. SN# 5953-61132. Tool ID# DNS-MP; Equipment Located in Nijmegen, The Netherlands

DNS SC-80AW Litho-Coater; Vintage: June 1994; 200mm wafer. SN# 53700-2713. Tool ID# DNS-SCW80A-4-ISA1; Located in Nijmegen, The Netherlands

Applied Materials P5000 Etch-Poly; 3xMxP Poly Chambers, 200mm wafer; Vintage: April 16,1994; SN# 6651; Tool ID# AMT-5000-ISA1; Equipment Located in Nijmegen, The Netherlands

Novellus Sabre Classic ECP; 200mm wafer; SN# 98-50-CU0007; Located in Nijmegen, The Netherlands

LAM Research; Model; Ontrak DSS 200 Series 1 Process- Wet-Scrubber wafer size 200mm Serial # 5848 Tool ID # ONT-DSS3-PFA2 Equipment located in Nijmegen, The Netherlands

LAM Research; Model; Ontrak DSS 200 Series 1 Process-Wet- Scrubber wafer size 200mm Serial# 5250-1 Tool ID # ONT-DSS4-PFA2 Equipment located in Nijmegen, The Netherlands

ZEISS; Model; Axiotron Process- Metrology-Inspection, wafer size 200mm Tool ID# D214054 Equipment located in Nijmegen, The Netherlands

ZEISS; Model; Axiotron Process- Metrology-Inspection, wafer size 200mm Tool ID# D214472 Equipment located in Nijmegen, The Netherlands

ZEISS; Model; Axiotron Process- Metrology-Inspection, wafer size 200mm Tool ID# D214475 Equipment located in Nijmegen, The Netherlands

ZEISS; Model; Axiotron Process- Metrology-Inspection, wafer size 200mm Tool ID# D214420 Equipment located in Nijmegen, The Netherlands

ZEISS; Model; Axiotron Process- Metrology-Inspection, wafer size 200mm Tool ID# D214055 Equipment located in Nijmegen, The Netherlands

Kokusai; Qty: (2) Model BTI Apogee; Process-Furnace-LPCVD, wafer size 200mm Vintage: 1996 SN# #'s VATT7, VATT20, VATT21, Tool ID #'s D214263, D214252, D214261 Parts missing; Equipment located in Nijmegen, The Netherlands

Kokusai; Qty: (3) Model BTI Apogee; Process-Furnace-LPCVD, wafer size 200mm Vintage: 1996 SN# #'s VATT7, VATT20, VATT21, Tool ID #'s D214263, D214252, D214261 Parts missing; Equipment located in Nijmegen, The Netherlands

Kokusai; Model; BTI Apogee Process-Furnace-LPCVD wafer size 200mm- missing parts- Vintage: 1997 SN# VATT31 Tool ID # D214254 Equipment located in Nijmegen, The Netherlands

Lam Research Rainbow 4420 Poly-Nitride Etcher / Wafer Size: 200mm (8-inch) / Vintage: 1992 / Serial Numbers: 2461 and 2488 / Stand alone configuration / Software: Classic Rainbow rev. 7.3 / wafer flats or Clamp-ring / Plumbed for gases: Cl2, CHF3, He, N2, O2, SF6, CHF3, HBr / 208 Volts, 3-phase, 30 Amps / Ergonomic cassette-tit option / Equipment was in working condition when shut down / Equipment Stored in Cleanroom / Located in Corvallis, Oregon. (qty. 2)

Lam Research 4500; Oxide Etcher / Wafer Size: 200mm (8-inch) / Vintage: 1991- Serial Numbers: 2313, 2314, 2254, 2216/ Vintage: 1990. SN# 2249/ Stand alone configuration / Software: Envision rev. 6.4.1.2 / wafer held by Electrostatic Chuck / Plumbed for gases: Ar, He, N2, O2, CF4, CHF3 / 208 Volts, 3-phase, 30 Amps / Ergonomic cassette-tit option / Equipment was in working condition when shut down / Equipment Stored in Cleanroom / Located in Corvallis, Oregon. (qty. 9)

Lam Research 4520; Oxide Etcher / Wafer Size: 200mm (8-inch) / Vintage: 1992 / Serial Numbers: 2476, 2477, 2504 and 2482 Stand alone configuration / Software: Classic Rainbow rev. 7.3 / wafer held by Electrostatic Chuck / Plumbed for gases: Ar, He, N2, O2, CF4, CHF3 / 208 Volts, 3-phase, 30 Amps / Ergonomic cassette-tit option / Equipment was in working condition when shut down / Equipment Stored in Cleanroom / Located in Corvallis, Oregon. (qty. 4)

Akrion Systems V3 Automated Wet Bench; Wafer Size: 200mm (8-inch) / Vintage: 2003 / Serial Number: 11TA03A007 , Machine ID# AV3WPRC002 Number of Tanks: 2 / Tank-1 Process Tank configured for: Sulfuric Peroxide / Tank2- Combined Quick-Dump/Rinse and Lucid Dryer (IPA Dryer) / Software: IDX / Equipment was in working condition when shut down / Equipment Stored in Cleanroom / Located in Corvallis, Oregon.

Akrion Systems V3 Automated Wet Bench; Automated Wet Bench / Wafer Size: 200mm (8-inch) / Vintage: 2005 / Serial Number: 13670 A005 , Machine ID# AV3WPRC010 / Number of Tanks: 2 / Tank-1: Process Tank configured for: SC1 with Megasonics / Tank2- Combined Quick-Dump/Rinse and Lucid Dryer (IPA Dryer) / Software: IDX / Equipment was in working condition when shut down / Equipment Stored in Cleanroom / Located in Corvallis, Oregon.

PRI Automation 7700; Reticle Handler / Vintage: 1998 / Serial Number: 49872197 / Capacity: 1292 pods / Pod Size: 7" x 7" x 5.9" / Stocker Matrix Designation RN1995/42-12MF / Operating System: Windows NT 3.51 / Robot Engine: 1.3 pa S / Stocker GUI: 1.3 pa S / Equipment was in working condition when shut down / Equipment Stored in Cleanroom / Located in Corvallis, Oregon.

KLA-Tencor FT-750; Thin Film Thickness Measurement / Vintage: 1995 / Serial Number: 950754FT750 / Wafer Size: 200mm (8-inch) / Cognex Vision System / Software: Stat Test 7.31 / 120V 60 Hz single-phase / Equipment was in working condition when shut down / Equipment Stored in Cleanroom / Located in Corvallis, Oregon.

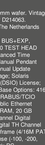
Thermawave Corp. TP400; Implant Monitor / Vintage: 1996 / Serial Number: 3023 / Software: IMS 1.60 / 220V 1-phase, 50/60 Hz 20 Amps / Equipment was in working condition when shut down / Equipment Stored in Cleanroom / Located in Corvallis, Oregon.

Polyflow Engineering S-80S; Chemical Delivery System / Accepts up to two (2) barrels (55-gallon Drum) or previously used to dispense Nitric Acid / Connections: CDA, NC, Drain (4), Exhaust, Pumped, Vent-Dual / 120V 60 Hz Single-Phase / Serial Number: 1543 / Equipment was in working condition when shut down / Equipment Stored in Cleanroom / Located in Corvallis, Oregon.

Semitest SCA 2500; Surface Charge Analyzer / Serial Number: 1082 / Single-Phase 50/60 Hz, 1000 VA Max., 100-120 VAC / Vacuum 20 inches of mercury / Includes Model: AL-1/PA Automatic Wafer Loader/ Robot: Brooks model 001-0000-39, serial 9707-1655 / Equipment was in working condition when shut down / Equipment Stored in Cleanroom / Located in Corvallis, Oregon.

Despatch Industries LEB2-30-3; Curing Oven, 240 Volt, Single-Phase, 60Hz, 20 Amps / HTR-4800 Watts / Equipment was in working condition when shut down / Equipment Stored in Cleanroom / Located in Corvallis, Oregon.

Polyflow Engineering S-61G; Vertical Furnace Quartz Tube cleaner / Serial Number: 1640 / Software Rev. 7.03 / Previously Used with Nitric Acid, and Hydrofluoric (HF) Acid / connections: Dr Water, NC, Acid-In, Drain(s), Exhaust (3) / 120 V 60 Hz Single-Phase / Equipment was in working condition when shut down / Equipment Stored in Cleanroom / Located in Corvallis, Oregon.



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